

Abstract**Method of Cleaving GaN/Sapphire for Forming Laser Mirror Facets**

- 5 A method of fabricating a cleaved facet of a laser device having a substrate and at least one GaN-based layer formed upon a first surface of the substrate, said method including the following steps:
- 10 • cutting linear grooves into a second surface of the substrate, said grooves being in alignment with vertical planes of said substrate;
 and
- cleaving said substrate and said at least one GaN-based layer along said vertical planes;
- wherein said cutting is effected by a laser beam from an external laser source.